

**Notice of References Cited**

Application/Control No.

10/077,258

Applicant(s)/Patent Under  
Reexamination  
MO ET AL.

Examiner

Yennhu B Huynh

Art Unit

2813

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
X	A	US-4774556	09-1988	Fujii et al.	257/316
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
X	N	JP63288047	11-1988	Japan	Mori	HO1L/21/95
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
X	U	Kao et al., "Two-Dimensional Thermal Oxidation of Silicon-II Modeling Stress Effects in Wet Oxides", IEEE, Vol. ED-35, No.1, 1/1988i
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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